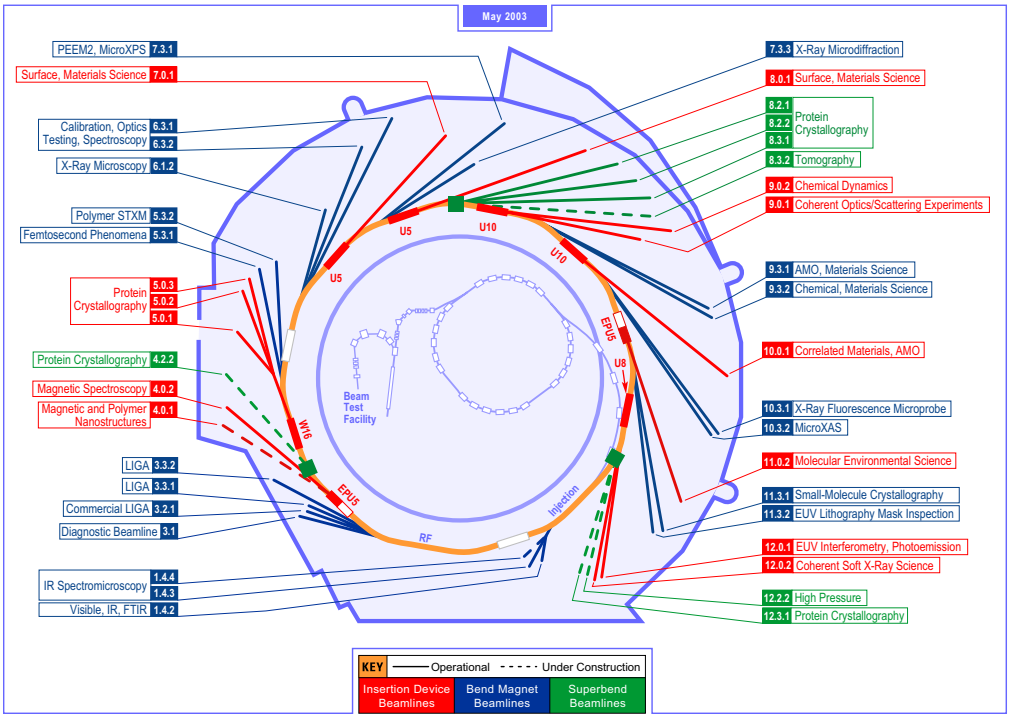
ADVANCED LIGHT SOURCE

Current and Planned Beamlines for Users Through 2003

Berkeley Lab • University of California

Beamline Overview

BEAMLINES	Bend-Magnet	Superbend	Wiggler	Undulator	IR/VIS/UV
Now	20	3	3	8	2
2003	21	7	3	9	3
ENERGY RANGE	30 eV – 20 keV	6 – 18 keV	3.5 – 14 keV	5 – 1800 eV	0.005 – 6.2 eV



Beamline designations x.y.z *refer to storage ring sector number x, port number y, and branch number z. There are 12 sectors. Ports 0 are insertion-device ports, 10 of which are available for undulators and wigglers; ports 1, 2, and 3, are bend-magnet or superbend ports; ports 4 are potential infrared ports.*

Experimenters from industry, universities, and government laboratories are welcome at the ALS. Beamlines are being developed and operated by user groups (participating research teams, or PRTs) working with the ALS staff. There are 40 user beamlines either currently in place or planned through 2003, as well as a diagnostic beamline for accelerator studies. Access to beamlines by independent investigators not associated with a PRT is obtained in two ways: by submitting a research proposal to the ALS that will be peer reviewed or by establishing a collaboration with members of the appropriate PRT. The latter is often the most convenient way for new users to gain experience. Investigators may bring their own experimental chambers or use those provided by the ALS or the PRTs. For additional information, see the data sheets for individual beamlines (data tables are also on the World Wide Web at *www-als.lbl.gov/als/als_users_bl/bl_table.html* or consult the contacts listed on the reverse side. ■

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Beamline	Source[1]	Energy Range	Available
1.4.2	Bend	0.002–3 eV	Now
1.4.3	Bend	0.02–1 eV	Now
1.4.4	Bend	0.05–1 eV	2003
3.1	Bend	1–2 keV	Now
3.2.1	Bend	3–12 keV	Now
3.3.1	Bend	3–12 keV	Now
3.3.2	Bend	1–20 keV	Now
4.0.2	EPU5	52–1900 eV	Now
4.2.2	Superbend	6–18 keV	2003
5.0.1	W16	12.4 keV	Now
5.0.2	W16	3.5–14 keV	Now
5.0.3	W16	12.4 keV	Now
5.3.1	Bend	1.8–12 keV	Now
5.3.2	Bend	200–650 eV	Now
6.1.2	Bend	300–900 eV	Now
6.3.1	Bend	500–2000 eV	Now
6.3.2	Bend	50–1300 eV	Now
7.0.1	U5	50–1200 eV	Now
7.3.1.1	Bend	175–1500 eV	Now
7.3.1.2	Bend	175–1500 eV	Now

Beamline	Source[1]	Energy Range	Available
7.3.3	Bend	6–12 keV	Now
8.0.1	U5	65–1400 eV	Now
8.2.1	Superbend	6–18 keV	Now
8.2.2	Superbend	6–18 keV	Now
8.3.1	Superbend	2.4–18 keV	Now
8.3.2	Superbend	3–60 keV	2003
9.0.1	U10	200–800 eV	Now
9.0.2	U10	5–30 eV	Now
9.3.1	Bend	2.2–6 keV	Now
9.3.2	Bend	30–1400 eV	Now
10.0.1	U10	17–320 eV	Now
10.3.1	Bend	3–20 keV	Now
10.3.2	Bend	2.5–17 keV	Now
11.0.2	EPU5	75–2000 eV	Now
11.3.1	Bend	6–17 keV	Now
11.3.2	Bend	50–1000 eV	Now
12.0.1	U8	60–320 eV	Now
12.0.2	U8	200–1000 eV	2003
12.2.2	Superbend	6–40 keV	2003
12.3.1	Superbend	6–18 keV	2003

[1] Sources: Bend – bend magnet.
Superbend – superconducting bend magnet.
EPUx – x-cm-period elliptically polarizing undulator.
Ux – x-cm-period undulator.
Wx – x-cm-period wiggler.

To obtain a proposal form, go to www-als.lbl.gov/als/quickguide/independinvest.html.

Scientific Program

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